



In re Application of:  
Latchford, et al.

Serial No.: 09/921,938

Confirmation No.: 8367

Filed: August 2, 2001

For: Photolithography Scheme Using a Silicon Containing Resist

Box AF  
Assistant Commissioner for Patents  
Washington, D.C. 20231

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Group Art Unit: 1752

Examiner: A. C. Walke

**CERTIFICATE OF MAILING**

37 CFR 1.8

I hereby certify that this correspondence is being deposited on October 7, 2002 with the United States Postal Service as First Class Mail in an envelope addressed to: Box AF  
Commissioner for Patents, Washington, D.C. 20231.

10/7/02

Date \_\_\_\_\_

Unit 2, 2hr

Signature \_\_\_\_\_

Dear Sir:

## PETITION FOR TWO-MONTH EXTENSION OF TIME

Applicant respectfully petitions the Commissioner under 37 CFR 1.136(a) to grant a two-month extension of time to and including October 7, 2002, in which to file the Notice of Appeal.

This form is filed in duplicate. The Commissioner is authorized to charge the fee of \$290.00 for the two month extension (following a prior one-month extension) and any additional fees which may be required for this submission to Deposit Account No. 20-0782/AMAT/4227.P1/DSM/BCVD/KMT.

Respectfully submitted,

Kind 2. 2. 2.

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